

PROCESSING APPARATUS

ABSTRACT

Provided is a technique for processing a substrate in a short time. A processing apparatus 1 includes a table 10 configured to hold a substrate Wf such that a surface to be processed of the substrate faces upward, a table rotation device 20 configured to rotate the table, a plurality of heads 30a, 40a to each of which a processing pad Pd1, Pd2 is attached, the processing pad having an area smaller than an area of the surface to be processed of the substrate, a plurality of head rotation devices 50a, 55a, a plurality of pressing devices 60a, 65a, each of the plurality of pressing devices has an electromagnetic actuator configured to apply a pressing force to a corresponding one of the plurality of heads by utilizing electromagnetic force, and a plurality of swing devices 70a, 80a.

Selected Drawing: Fig. 1